

U.S.S.N. 10,656,585

Specification Amendments

Please replace the Title of the Invention with the following rewritten Title:

APPARATUS AND METHOD FOR PRE-CONDITIONING CMP POLISHING PAD

Please replace paragraph beginning on line 14, page 8 with the following rewritten paragraph:

The conventional conditioning disk 68 may be of several different types. A conventional brazed grid-type conditioning disk is formed by embedding or encapsulating diamond particles in random spacings with each other in the surface of a stainless steel substrate. A conventional diamond grid-type conditioning disk is formed by embedding cut diamonds at regular spacings in a nickel film coated onto the surface of a stainless steel substrate. The diamonds are typically coated with a diamond-like carbon (DLC) layer.

Please replace paragraph beginning on line 11, page 11 with the following rewritten paragraph:

Another object of the present invention is to provide a new

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and improved apparatus and method which saves time in the pre-conditioning of a polishing pad on a CMP apparatus.